



IFW/18

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q77321

Hiroshi OKUMURA

Appln. No.: 10/773,333

Group Art Unit: 2811

Confirmation No.: 8920

Examiner: Unknown

Filed: February 09, 2004

For: THIN FILM TRANSISTOR SUBSTRATE AND METHOD FOR MANUFACTURING
THE SAME

RESPONSE TO RESTRICTION REQUIREMENT

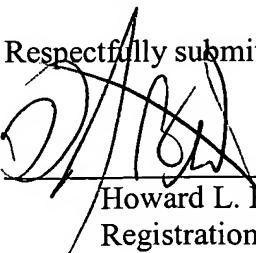
Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated December 20, 2004, in which the Examiner has required a restriction, Applicant responds by electing Group I, *i.e.*, claims 1-17, drawn to a thin film transistor substrate. This election is made without prejudice to the filing of a divisional application directed to the non-elected claims.

Prompt and favorable action on the elected claims is now respectfully requested.

Respectfully submitted,


Howard L. Bernstein
Registration No. 25,665

SUGHRUE MION, PLLC
Telephone: (202) 293-7060
Facsimile: (202) 293-7860

WASHINGTON OFFICE

23373

CUSTOMER NUMBER

Date: January 31, 2005